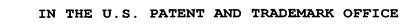
PATENT 8017-1096



Yasuaki TSUCHIYA et al.

Conf. 4719

Application No. 10/622,735

application of

Group 1755

Filed July 21, 2003

SLURRY FOR POLISHING COPPER-BASED METAL

## SUPPLEMENTAL NFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 July 1, 2004

Sir:

In compliance with Rules 1.97 and 1.98, and in fulfillment of the duty of disclosure under Rule 1.56, the accompanying documents, copies of which are attached to this statement, are made of record on the enclosed Form PTO-1449.

A concise explanation of the relevance of these items is that these references were cited by the Taiwanese Patent Office in an Official Action (U.S. Patent No. 6,171,352 is the U.S. counterpart for Taiwanese Patent 455626). A copy of the Taiwanese Official Action in which they were cited is attached hereto. An English translation of the Taiwanese Official Action is also attached hereto.

Respectfully submitted,

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(703) 979-4709

INFO	RMA	TION DISCLOSU	ITATION	Attorney Docket No.: 8017-1096			Application No.: 10/622,735					
IN AN APPTECATION						Applicant: Yasuaki TSUCHIYA et al.						
(Use several sheets if necessary)  JUL 0 1 2004 E  U.S. PATEN						Filing Date: July 21, 2003			Group Art Unit: 1755			
U.S. PATENT DOCUMENTS												
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)												
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.												

<sup>\*</sup> Abstract provided for the Examiner's convenience